



INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

Form PTO-1449 (Modified)
(Use several sheets if necessary)

COMPLETE IF KNOWN

Application Number	09/651,779
Confirmation Number	2448
Filing Date	August 30, 2000
First Named Inventor	Scott E. Moore
Group Art Unit	3723
Examiner Name	Dung V. Nguyen
Attorney Docket No.	108298515US

Sheet 1 of 4

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
	AA	U.S. Application No. 09/651,808 (Atty. Docket No. 4373US)		Chopra et al.	Filed 08/30/2000	
	AB	U.S. Application No. 09/653,392 (Atty. Docket No. MTI-31044)		Chopra et al.	Filed 08/31/2000	
	AC	U.S. Application No. 09/887,767 (Atty. Docket No. 10829.8515US2)		Lee et al.	Filed 06/21/2001	
	AD	U.S. Application No. 09/888,002 (Atty. Docket No. 10829.8515US3)		Lee et al.	Filed 06/21/2001	
	AE	U.S. Application No. 09/888,084 (Atty. Docket No. 10829.8515US1)		Lee et al.	Filed 06/21/2001	
	AF	U.S. Application No. 10/230,463 (Atty. Docket No. 10829.8672US)		Lee et al.	Filed 08/29/2002	
	AG	U.S. Application No. 10/230,602 (Atty. Docket No. 10829.8674US)		Chopra	Filed 08/29/2002	
	AH	U.S. Application No. 10/230,628 (Atty. Docket No. 10829.8673US)		Lee et al.	Filed 08/29/2002	
	AI	U.S. Application No. 10/230,970 (Atty. Docket No. 10829.8515US6)		Lee et al.	Filed 08/29/2002	
	AJ	U.S. Application No. 10/230,972 (Atty. Docket No. 10829.8515US7)		Lee et al.	Filed 08/29/2002	
	AK	U.S. Application No. 10/230,973 (Atty. Docket No. 10829.8515US8)		Lee et al.	Filed 08/29/2002	
	AL	5,244,534		Yu et al.	09/14/1993	
	AM	5,300,155		Sandhu et al.	04/05/1994	
	AN	5,567,300		Datta et al.	10/22/1996	
	AO	5,575,885		Hirabayashi et al.	11/19/1996	

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Sheet 2 of 4

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	AP	5,648,381		Dean et al.	04/08/1997	
	AQ	5,676,587		Landers et al.	10/14/1997	
	AR	5,681,423		Sandhu et al.	10/28/1997	
	AS	5,780,358		Zhou et al.	07/14/1998	
	AT	5,807,165		Uzoh et al.	09/15/1998	
	AU	5,840,629		Carpio	11/24/1998	
	AV	5,846,398		Carpio	12/08/1998	
	AW	5,863,307		Zhou et al.	01/26/1999	
	AX	5,897,375		Watts et al.	04/27/1999	
	AY	5,930,699		Bhatia	07/27/1999	
	AZ	5,934,980		Koos et al.	08/10/1999	
	BA	5,954,975		Gadien et al.	09/21/1999	
	BB	5,954,997		Kaufman et al.	09/21/1999	
	BC	5,972,792		Hudson	10/26/1999	
	BD	6,001,730		Farkas et al.	12/14/1999	
	BE	6,039,693		Chopra	03/21/2000	
	BF	6,046,099		Gadien et al.	04/04/2000	
	BG	6,051,496		Jang	04/18/2000	
	BH	6,060,386		Givens	05/09/2000	
	BI	6,060,395		Skrovan et al.	05/09/2000	
	BJ	6,063,306		Kaufman et al.	05/16/2000	
	BK	6,066,559		Gonzalez et al.	05/23/2000	
	BL	6,068,787		Grumbine et al.	05/30/2000	
	BM	6,083,840		Mravic et al.	07/04/2000	

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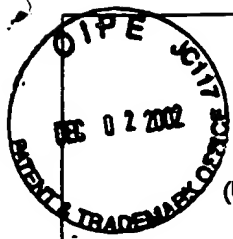
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		NUMBER	Kind Code (if known)			
	BN	6,100,197		Hasegawa	08/08/2000	
	BO	6,103,628		Talieh	08/15/2000	
	BP	6,117,781		Lukanc et al.	09/12/2000	
	BQ	6,143,155		Adams et al.	11/07/2000	
	BR	6,176,992	B1	Talieh	01/23/2001	
	BS	6,196,899	B1	Chopra et al.	03/06/2001	
	BT	6,206,756	B1	Chopra et al.	03/27/2001	
	BU	6,218,309	B1	Miller et al.	04/17/2001	
	BV	6,260,994	B1	Chopra et al.	06/26/2001	
	BW	6,273,786	B1	Chopra et al.	08/14/2001	
	BX	6,276,996	B1	Chopra	08/21/2001	
	BY	6,287,974	B1	Miller	09/11/2001	
	BZ	6,313,038	B1	Chopra et al.	11/06/2001	
	CA	6,328,632	B1	Chopra	12/11/2001	

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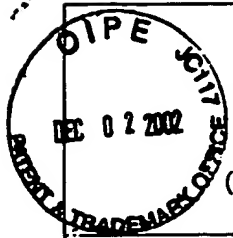
FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.	Foreign Patent or Application		Name of Patentee or Applicant of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Office	NUMBER				
	CB	WO	00/26443	Talieh	05/11/2000		
	CC	WO	00/28586	Chopra	05/18/2000		
	CD	WO	00/32356	Talieh	06/08/2000		
	CE	WO	00/59008	Talieh	10/05/2000		
	CF	WO	00/59682	Talieh	10/12/2000		

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T

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	CG	FRANKENTHAL, R.P. and EATON, D.H., "Electroetching of Platinum in the Titanium-Platinum-Gold Metallization on Silicon Integrated Circuits", <i>Journal of The Electrochemical Society</i> , Vol. 123, No. 5, pp. 703-706, May 1976.	
	CH	BERNHARDT, A.F., CONTOLINI, R.J., MAYER, S.T., "Electrochemical Planarization for Multi-Level Metallization of Microcircuitry," <i>Circuitree Journal</i> , Vol. 8, No. 10, pp. 38, 40, 42, 44, 46, and 48, Oct. 1995.	
	CI	HUANG, C.S. et al., "A Novel UV Baking Process to Improve DUV Photoresist Hardness", pp. 135-138.	
	CJ	McGraw-Hill, <i>Concise Encyclopedia of Science & Technology</i> , Sybil P. Parker, Editor-in-Chief, Fourth Edition, p. 367, McGraw-Hill, New York, New York, 1998.	
	CK	ATMI Table of Contents, presented at the Semicon West '99 Low-Dielectric Materials Technology Conference, July 12, 1999, pp. 13-25.	
	GL	KONDO, S. et al., "Abrasive-Free Polishing for Copper-Damascene Interconnection", <i>Journal of the Electrochemical Society</i> , 147 (10) 3907-3913 (2000)	
	CM	Micro-Photonics, Inc., CSM Application Bulletin, "Low-load Micro-Scratch Tester (MST) for characterisation of thin polymer films", http://www.microphotonics.com/mstABpoly.html , 7/25/2002, 3 pages.	
	CN	Micro-Photonics, Inc., "CSM Nano Hardness Tester", http://www.microphotonics.com/nht.html , 7/29/2002, 6 pages.	
	GO	PhysicsWorld Table of Contents, PhysicsWeb, "Hard Materials", http://physicsweb.org/box/world/11/1/11/world-11-1-11-1 , 7/29/2002, 1 page.	

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